

APPENDIX B

Instructions for electronic publication-ready papers

All papers will be printed in publication-ready format. Publication-ready copy should be prepared according to the following instructions. Please read these carefully, as publication-ready copy that does not conform to these instructions will be returned for correction.

(1) The paper should be submitted according to Section 3 of Notes for Authors. You do not need to prepare the publication-ready copy until your paper has been **accepted** by the Co-editor.

(2) The style of a publication-ready paper in the *Journal of Synchrotron Radiation* is shown on the following pages. The detailed typographic specifications are as follows:

Layout details

Page size (text area):	183 × 238 mm
Column width:	88 mm
Space between columns:	7 mm

Fonts and spacing

Title:	12 pt bold Helvetica
Authors:	10 pt bold Helvetica
Affiliations:	<i>9 pt oblique Helvetica</i>
Abstract:	9 pt Times Roman
Keywords:	8 pt bold Helvetica
Headings	
Level 1:	8 pt bold Helvetica, aligned left
Level 2:	8 pt bold Helvetica, aligned left
Level 3:	8 pt bold Helvetica, at start of paragraph
Text:	9 pt Times Roman
References:	8 pt Times Roman
Figure captions:	8 pt Times Roman
Table captions:	8 pt Times Roman
Table text:	7 pt Times Roman
Footnotes:	8 pt Times Roman

If you do not have Helvetica fonts available, please use Univers or another sans-serif font.

(3) Electronic templates (L^AT_EX and WORD) are available by ftp from the address <ftp.iucr.org> in the directory 'templates/jsr'. The above styles are already set up in these templates.

(4) Once your paper has been accepted, the Co-editor will ask you to provide (a) the completed publication-ready copy, (b) an electronic version of the paper in L^AT_EX or WORD, (c) originals of all figures and (d) electronic versions of all figures in PostScript, Encapsulated PostScript or TIFF format. Please send the material to the Co-editor in a rigid card envelope to ensure it is not damaged in the post.

(5) When the publication-ready copy has been approved by the Co-editor, it will be forwarded to the Editorial Office in Chester for publication. If additional material is required by the Editorial Office, it should be submitted following the procedures given in Section 3.11 of Notes for Authors.

Table 1
Specifications of optical components.

Component	Specifications	
Mo/Si MLM	Substrate	Si wafer (40 × 40 mm)
	Number of layers	20
	Period, d	12.5 nm (12.4 nm) [†]
	Thickness ratio, Mo/Si	3/7 (3.25/6.75) [†]
	Interface roughness, σ	(0.4 nm) [†]
Mo/C MLM	Substrate	Si wafer (40 × 40 mm)
	Number of layers	50
	Period, d	7.5 nm (7.9 nm) [†]
	Thickness ratio, Mo/C	1/1 (5.5/4.5) [†]
	Interface roughness, σ	(0.4 nm) [†]

[†] Values determined by fitting to the observed Cu $K\alpha$ line diffraction curves.

Mo/C (for 85–120 eV) MLMs. This energy region includes the core-electron binding energies of Al (2s: 119 eV; 2p: 74 eV) and Si (2p: 103 eV), which are important materials in semiconductor processes. To reduce the background noise in the low-energy region due to the total reflection, it is necessary to use the MLM at low incident angles. The Mo/Si and Mo/C MLMs were therefore designed so that they could cover the Al 2s and 2p and Si 2p binding energies in the incident angle range of 10–50°. Moreover, the detailed structural parameters have been determined so that the reflectivity is high and the reflectance is nonreciprocal. Both Mo/Si and Mo/C MLMs were designed with the parameters listed in Table 1. The reflectivity was calculated using the Cu $K\alpha$ line diffraction data, and the reflectance was calculated using the Cu $K\alpha$ line diffraction data. The reflectivity and reflectance of the Mo/Si and Mo/C MLMs are listed in Table 2.

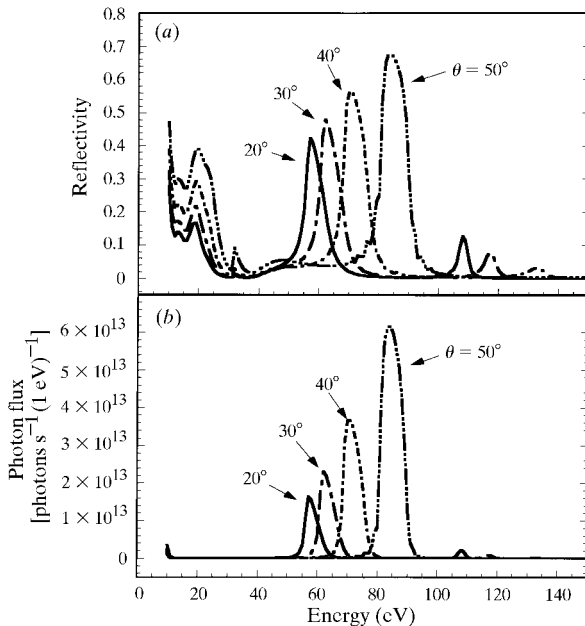


Figure 2
(a) Calculated reflectivity for the Mo/Si MLM and (b) output photon flux of the monochromator using Mo/Si MLMs plus C filter for a 100 mA ring current and a 16.56×12.79 mrad² acceptance angle of the pre-mirror, assuming that the monochromator is set up in the beamline BL-4A1 of the UVSOR.

2.3. Thin-film filters

The transmission characteristics of the thin-film filter have been calculated for several materials and it has been found that carbon and molybdenum are useful for reducing the background noise at energies below 70 eV. The transmission spectra calculated for 100 nm-thick carbon and molybdenum film filters are shown in Figs. 1(a) and 1(b), respectively.

3. Performance of the monochromator

The performance of the MLM monochromator, designed as described above, was evaluated by calculating what the basic characteristics, such as output photon flux, resolution, monochromaticity and tuning range, would be if the monochromator were set up as part of the beamline (BL-4A1) of the synchrotron radiation storage ring at the UVSOR. In this case, the beam emitted from the bending magnet is reflected by an elliptical mirror with a focal length of 40 cm and is focused on the monochromator. The horizontal and vertical beam sizes at the monochromator are 6.1 mm and 0.5 mm, respectively. The reflectivity and reflectance were calculated for a monochromator with the parameters listed in Table 1, as shown in Fig. 2(a) for the Mo/Si case. It is known that extremely large total-reflection components appear at less than 40 eV in the case of Mo/Si.

The output beam photon fluxes calculated for various incident angles are shown in Fig. 2(b) for the case of Mo/Si MLM plus C filter. It is clearly shown that the filter drastically reduces the low-energy background noise. It is less than 1% (3%) of the main flux, where the value in parentheses is for the case of Mo/C MLM plus Mo filter. The higher-order photons background noise is less than 4% (0.1%). The calculated photon flux is 1×10^{14} to 5×10^{14} photons s⁻¹ (3×10^{13} to 4×10^{13} photons s⁻¹) and the resolution is 5–9 eV (2–4 eV) FWHM. The calculated results are similar to those obtained with a typical undulator. Given that the MLM monochromator can select the photon energy continuously and that the mixing of higher-order photons is small, it is suggested that the present monochromator will be better than an undulator for use in synchrotron radiation experiments. We conclude from this work that the background noise due to the total reflection, which prevented the MLM monochromator from being used in the VUV low-energy region, can be sufficiently reduced by using double-crystal-type MLMs at low incident angles combined with a carbon or molybdenum thin-film filter.

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References

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